

DOCKET NO: 268668US26PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF	:
TAKAHIRO HORIGUCHI, ET AL.	: EXAMINER: DHINGRA, R. K.
SERIAL NO: 10/529,191	:
FILED: MARCH 24, 2005	: GROUP ART UNIT: 1792
FOR: SUBSTRATE PROCESSING APPARATUS	:

STATEMENT OF SUBSTANCE OF INTERVIEW UNDER MPEP § 713.04

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

The following is a statement of the substance of the interview conducted on March 18, 2010, in accordance with MPEP § 713.04. Examiner Dhingra contacted Applicants' representative on March 18, 2010, regarding a proposal for an Examiner's Amendment to place the application in condition for allowance. The proposed Examiner's Amendment is set forth on the attached partial claim listing. Aside from the amendment to Claim 11 set forth in the attached partial claim listing, the proposed Examiner's Amendment would change "55A" to "55C" in the brief description of the drawings where appropriate.

Applicants' representative provided authorization for the proposed Examiner's
Amendment on March 19, 2010.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, L.L.P.

A handwritten signature in black ink, appearing to read 'Steven P. Weihrouck', is written over a horizontal line.

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PROPOSED EXAMINER'S AMENDMENT

Claim 11: A semiconductor substrate processing apparatus comprising:

a processing vessel that defines a processing space therein;

a transparent case made of quartz and disposed within the processing vessel, the transparent case including a cylinder portion and a top plate covering a top part of the cylinder portion;

a heating element, contained inside the transparent case, to generate heat inside the transparent case for heating a substrate introduced into the processing space to a predetermined temperature;

a heater plate, mounted on an upper external surface of the top plate of the transparent case, to transmit the heat generated inside the transparent case to the substrate;

a substrate holding member having an axis penetrating the top plate of the transparent case and the heater plate and projecting from an upper surface of the heater plate, the axis having a plurality of arm portions to hold the substrate at a position spaced from and opposite to the upper surface of the heater plate located below the substrate; and

a rotational drive part configured to rotatively drive the axis of the holding member.